

Fig. 2

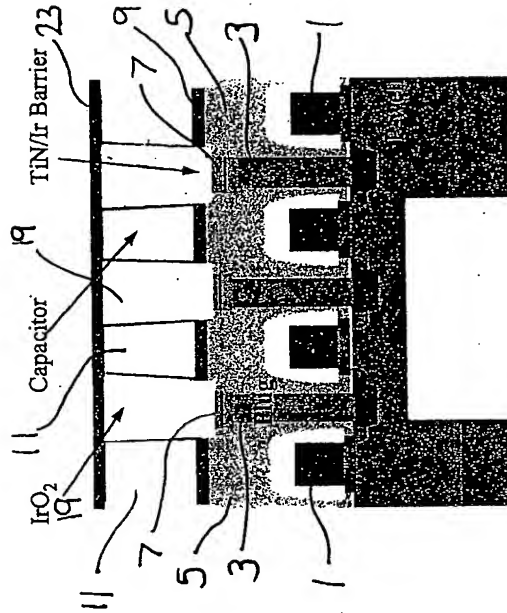


Fig. 1  
[PRIOR ART]

2/6

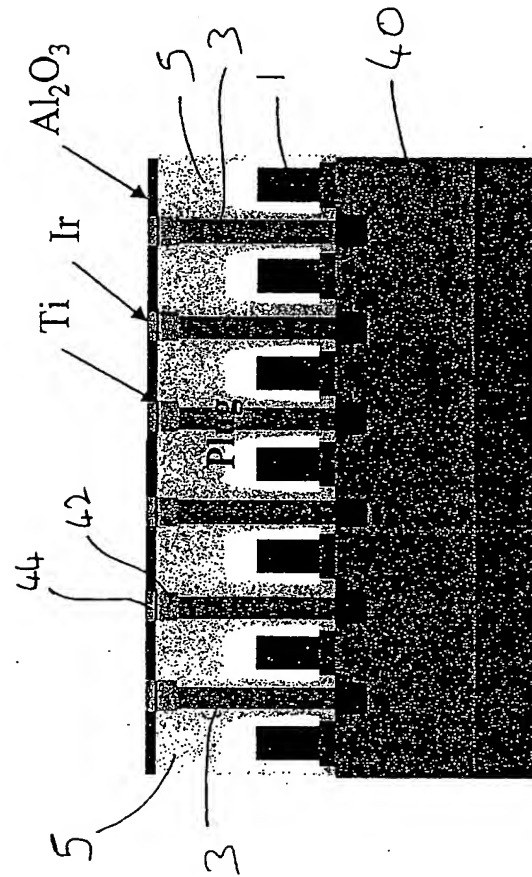


Fig. 3 Before Capacitor Process

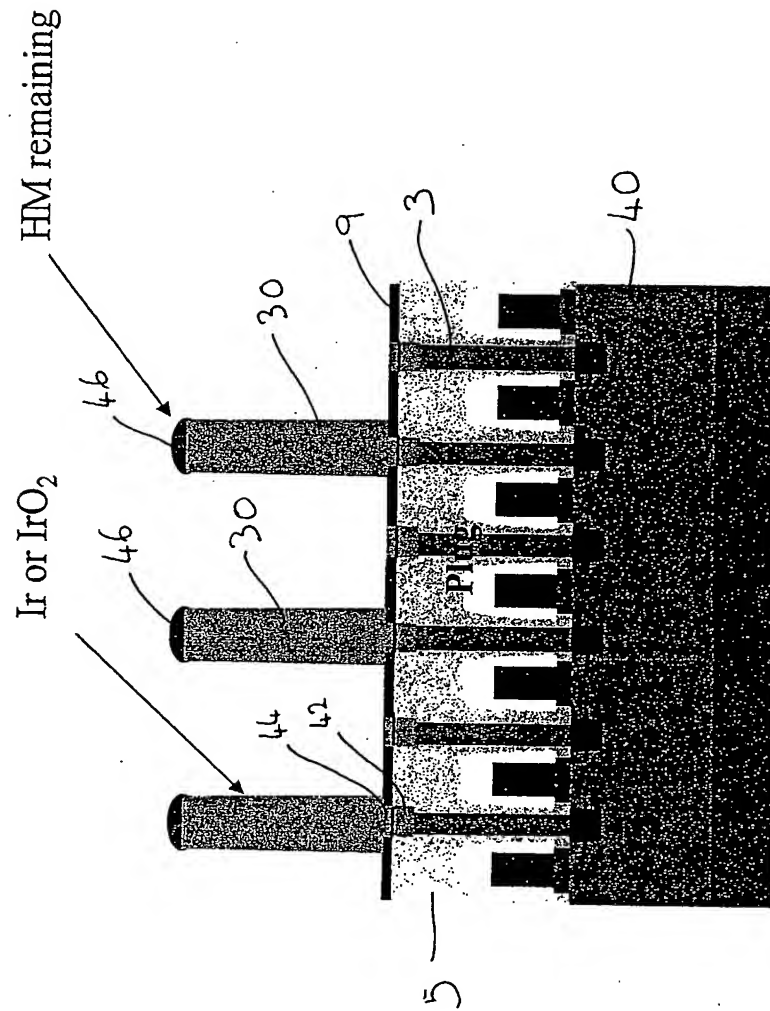


Fig. 4 Ir or IrO<sub>2</sub> Deposit and RIE

4/6

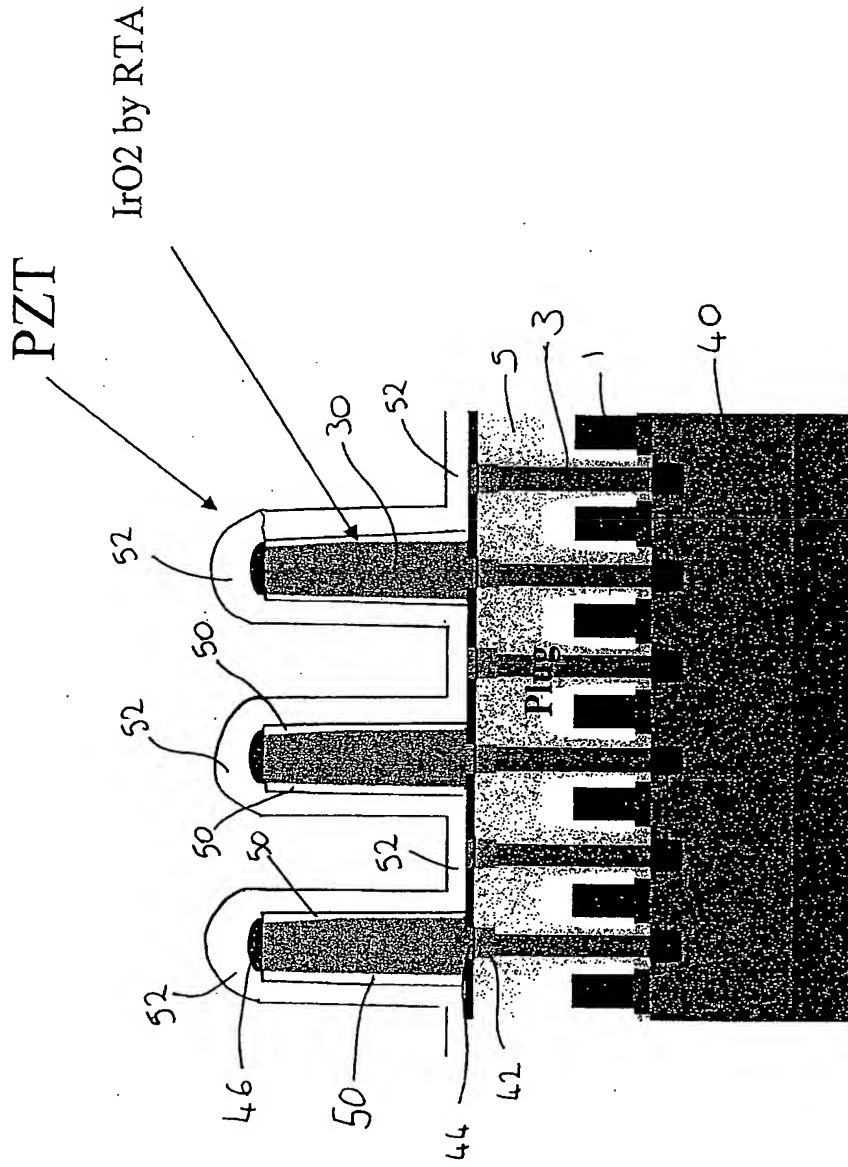


Fig 5 Making IrO2 on Ir surface  
(by RTA; if electrode is IrO2, RTA is  
not necessary)  
and PZT Deposit on Surface

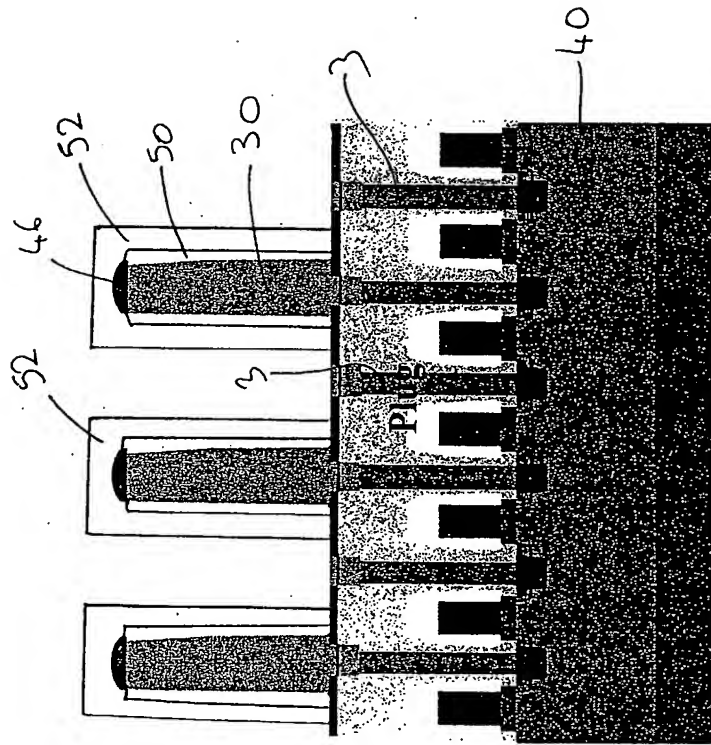


Fig. 6 PZT Etch Back

6/6

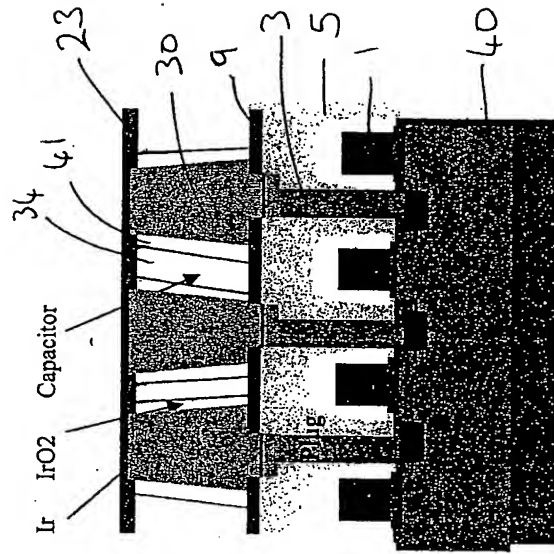


Fig. 7 Fill IrO2 and Fill Ir (Or Only fill IrO2)  
CMP and then Al2O3 deposit